

ERRATA

Erratum: “(110)-oriented Bi–Sr–Ca–Cu–O superconducting thin films prepared by metalorganic chemical vapor deposition” [J. Mater. Res. **8**, 978 (1993)]

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When this article appeared in the May issue of *Journal of Materials Research*, some incorrect fonts were inadvertently used to output the final version of page 983

of the article. The following is the corrected page, output with the appropriate fonts, as it should have appeared in the May issue.

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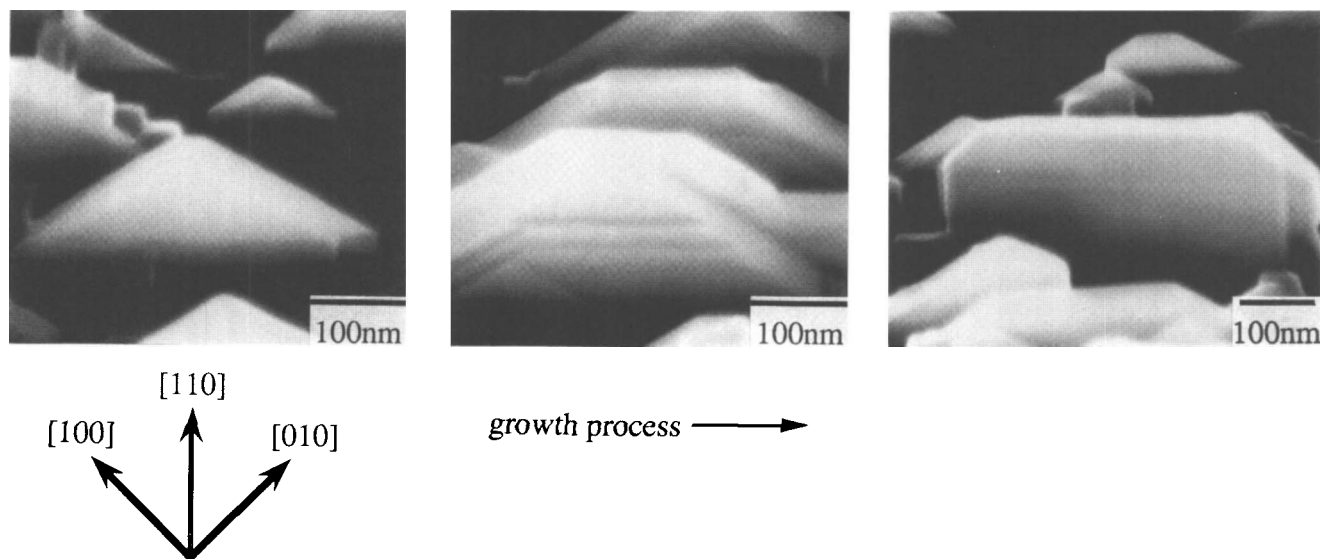


FIG. 8. SEM photographs of the (110)-oriented grain at the film surface tilted about 40°.

two-dimensional nucleation at the initial stage of the deposition by MOCVD, as shown in Fig. 9(a).⁹ On the other hand, Fig. 9(b) shows that the nucleation and the grain growth process of (110)-oriented films are different from the *c*-axis one, at least in the plane parallel to the substrate. We believe there are two types of growth processes; one depends on the coarsening of Fig. 9(b)-1, and the other is related to the coalescence of Fig. 9(b)-2. We plan to monitor *in situ* and analyze the gas phase exactly by means of a Quadrupole mass spectrometer

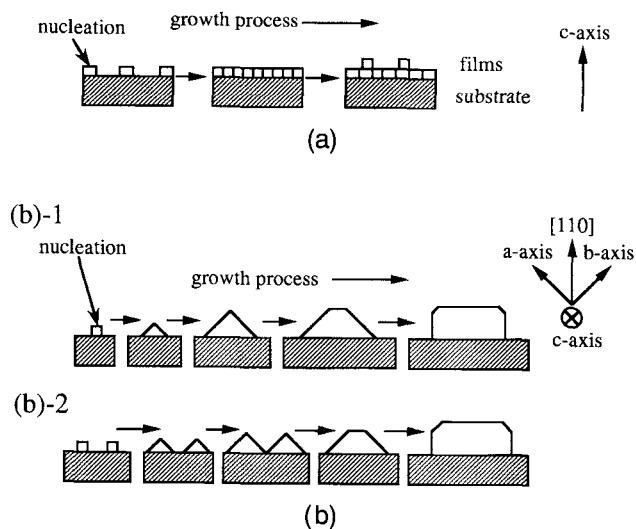


FIG. 9. A schematic diagram of the grain growth process at the initial stage. (a) Initial stage growth of the *c*-axis-oriented Bi-Sr-Ca-Cu-O grain. (b) Initial stage growth of the (110)-oriented Bi-Sr-Ca-Cu-O grain. There are two types of growth processes; one depends on the coarsening of (b)-1, and the other is related to the coalescence of (b)-2.

(Q-mass), so as to realize the relationship with the supersaturation.

Finally, we described the superconducting properties of these films. The resistivity versus the temperature of the films is shown in Fig. 10. 300 nm thickness film and 1 μm thickness films could only transport and apply a current along the [110] direction of the MgO substrate. The T_{c0} appeared in both samples: 30 K for a 300 nm thickness film and 60 K for a 1 μm thickness film, but 300 nm thickness samples had a long tailing. The critical current density (J_c) at 4.2 K is about 1×10^4 A/cm² on a 1 μm thickness sample and 1×10^2 A/cm² on a 300 nm thickness sample. We think the value of J_c depends on the density of (110)-oriented grains and the form of the grain boundary, so this value will rise by improving the film quality.

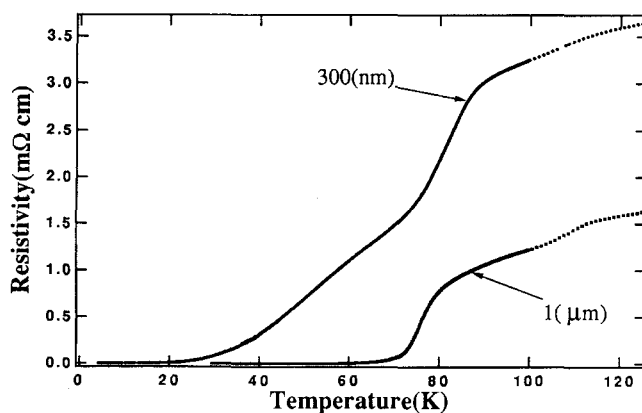


FIG. 10. ρ - T curves of the films of the film thickness 300 nm and 1 μm.